



FPD Materials & Components Japan TC Chapter and FPD Metrology Japan TC Chapter Joint Meeting Meeting Summary and Minutes

SEMI Japan Standards Fall 2015 Meetings Wednesday, November 11, 2015, 15:00-17:00 SEMI Japan, Tokyo, Japan

Next Committee Meeting FPD Materials & Components Japan TC Chapter: SEMI Japan Standards Winter 2016 Meetings Friday, February 5, 2016, 15:00-17:00 SEMI Japan, Tokyo, Japan

FPD Metrology Japan TC Chapter: SEMI Japan Standards Spring 2016 Meetings April, 2016 (TBD) SEMI Japan, Tokyo, Japan

Table 1 Meeting Attendees

Co-Chairs of FPD M&C Committee: Tadahiro Furukawa (Yamagata University), Yoshi Shibahara (Fujifilm) Co-Chairs of FPD Metrology Committee: Ryoichi Watanabe (Japan Display), Akira Kawaguchi (Otsuka Electronics) SEMI Staff: Naoko Tejima (SEMI Japan)

Company	Last	First	Company	Last	First
Sumitomo Bakelite	Eguchi	Toshimasa	Corning International	Okamura	Haruo
Yamagata University	Furukawa	Tadahiro	Fujifilm	Sato	Tadanobu
НОҮА	Ihara	Hirofumi	Fujifilm	Shibahara	Yoshi
Otsuka Electronics	Kawaguchi	Akira	SK Electronics	Shiojiri	Kazuya
Nitto Denko	Kobayashi	Shigeo	Sony	Tomioka	Satoshi
НОҮА	Nitobe	Kaname	Japan Display	Watanabe	Ryoichi
Konica Minolta.	Ochi	Keizo	SEMI Japan	Tejima	Naoko

* alphabetical order by last name

Table 2 Leadership ChangesFPD Materials & Components Japan TC Chapter

Group	Previous Leader	New Leader
IEPD Mask Task Force		Kazuya Shiojiri (SK Electronics) Hirofumi Ihara (HOYA)

FPD Metrology Japan TC Chapter

Group Previous Leader		New Leader
D31 Revision Task Force	Kose Tanahashi (Samsung Electronics) Masao Kochi (Highland) Keizo Ochi (Konica Minolta)	Keizo Ochi (Konica Minolta)





Table 3 Ballot Results

Passed ballots and line items will be forwarded to the ISC Audit & Review Subcommittee for procedural review. Failed ballots and line items were returned to the originating task forces for re-work and re-balloting.

FPD Materials & Components Japan TC Chapter

	Document #	Document Title	Committee Action
E	5555A	Revision to SEMI D50-0707, Test Method for Surface Hardness of FPD Polarizing Film with title change to: Test Method for Surface Hardness of FPD Components	Passed as ballotted

FPD Metrology Japan TC Chapter

None.

Table 4 Authorized Ballots

FPD Materials & Components Japan TC Chapter None.

FPD Metrology Japan TC Chapter

None.

Table 5 Authorized Activities

FPD Materials & Components Japan TC Chapter

Group	Type	SC/TF/WG	Details
	SNARF		Hirofumi Ihara (HOYA)

FPD Metrology Japan TC Chapter

None.

Table 6 New Action ItemsFPD Materials & Components Japan TC Chapter

Item #	Assigned to	Details
FPD M&C 151111-01	SEMI Staff	To forward adjudication result of Doc.#5555A to the ISC A&R Subcommittee for procedural review.
FPD M&C 151111-02	0	To send new SNARF of Measuring Method of Polarizing Film Configuration to SEMI 3 weeks before the next meeting (February 5).
FPD M&C 151111-03	SEMI Staff	To circular the above SNARF to TC members for their reviews.

FPD Metrology Japan TC Chapter

None.

[Common Part 1]

1 Welcome, Reminders, and Introductions

Tadahiro Furukawa, committee co-chair, called the meeting to order at 15:00. Self-introductions were made followed by the agenda review.





2 Required Meeting Elements

The meeting reminders on antitrust issues, intellectual property issues and holding meetings with international attendance were reviewed by SEMI staff, Naoko Tejima.

3 SEMI Staff Report

Naoko Tejima gave the SEMI staff report. This report included SEMI Global 2015/2016 Calendar of Events, Global Standards Meeting Schedule, NA Fall Standards Meetings Schedule, SEMICON Japan Outline & Standard Schedule, JRSC Highlight, 2015 Critical Dates for SEMI Standards Ballots, SEMI Standards Publications, A&R Ballot Review, Published Standards due for 5-year Reviews, 3-year SNRAF Project Period, Nonconforming Titles, and Contact Information.

Attachment: 01_SEMI_Staff_Report_151111

4 Liaison Reports

4.1 FPD Metrology Korea TC Chapter Report

No report was provided.

4.2 FPD Taiwan TC Chapter Report

Naoko Tejima reported for the FPD Taiwan TC Chapter. This report included Leadership, Current Committee Organization, Committee Highlight, Meeting Information and Contact Information.

Attachment: 02_TW_FPD_Liaison_Report_151111

[FPD Materials & Components Japan TC Chapter Part]

5 Review of Previous Meeting Minutes

The committee reviewed the minutes of the previous meeting held on July 27, 2015.

Motion:	To approve the minutes of the previous meeting as written.	
By / 2 nd :	Yoshi Shibahara (Fujifilm) / Shigeo Kobayashi (Nitto Denko)	
Discussion:	None	
Vote:	12 in favor and 0 opposed. Motion passed.	
Attachment:	03 JA FPD M+C Previous Mtg Minutes 151111	

6 Ballot Review

6.1 Doc.#5555A, Revision to SEMI D50-0707, Test Method for Surface Hardness of FPD Polarizing Film with title change to: Test Method for Surface Hardness of FPD Components.

This document passed committee review and will be forwarded to the ISC A&R SC for procedural review.

Action Item: SEMI staff to forward adjudication result of Doc.#5555A to the ISC A&R Subcommittee for procedural review.

Attachment: 04_Ballot_Report_for_5555A_151111

7 Task Force Reports

7.1 Polarizing Film Task Force

Yoshi Shibahara reported for the Polarizing Film Task Force. Of note:

• Doc.#5555A, Revision to SEMI D50-0707, Test Method for Surface Hardness of FPD Polarizing Film with title change to: Test Method for Surface Hardness of FPD Components, passed committee review as previously discussed. (See 6)

Shigeo Kobayashi reported for discussion about the Measuring Method of Polarizing Film Configuration. TF is planning to submit SNARF soon.

Action Item: Polarizing Film Task Force to send new SNARF of Measuring Method of Polarizing Film Configuration to SEMI 3 weeks before the next meeting (February 5).

Action Item: SEMI to circular the above SNARF to TC members for their reviews.

FPD Materials & Components Japan TC Chapter and FPD Metrology Japan TC Chapter Joint Meeting Minutes

3

November 11, 2015 SEMI Japan Tokyo, Japan





7.2 Flexible Display Task Force

Tadahiro Furukawa reported on progress for the Flexible Display Task Force. The following SNARF had been already reviewed for 2 weeks by global TC members and there were not any comments and reject. It was got final committee approval.

• New SNARF, Test Method of Water Vapor Barrier Property for Plastic Films with High Barrier for Electronic Devices

Motion:	To approve new SNARF, Test Method of Water Vapor Barrier Property for Plastic Films with High Barrier for Electronic Devices	
By / 2 nd :	Toshimasa Eguchi (Sumitomo Bakelite) / Tadanobu Sato (Fujifilm)	
Discussion:	None.	
Vote:	12 in favor and 0 opposed. Motion passed.	
Attachment:	05_New_SNARF_of_Water_Vapor_Barrier_Propoerty_150727	

7.3 Color Filter Task Force

Tadahiro Furukawa reported for the Color Filter Task Force that there were no particular things should be reported.

7.4 FPD Mask Task Force

Kaname Nitobe reported for the FPD Mask Task Force that there were no particular things should be reported.

Kaname Nitobe resigned the committee member because of personnel transfer. Hirofumi Ihara took over his position and was appointed as new co-leader.

Motion:	To approve to change the TF leader from Kaname Nitobe (HOYA) to Hirofumi Ihara (HOYA).
---------	--

By / 2nd: Kaname Nitobe (HOYA) / Kazuya Shiojiri (SK Electronics)

Discussion: None

Vote: 12 in favor and 0 opposed. Motion passed.

8 Old Business

8.1 Previous Meeting Action Items

Naoko Tejima reviewed the previous meeting action items.

Table 7 Previous Meeting Action ItemsFPD Materials & Components Japan TC Chapter

Item #	Assigned to	Details
FPD M&C 150727-01		To correct "Naomichi, Yamagishi, Japan <u>Business</u> Society" of "Table 1 Meeting Attendee" of the previous meeting minutes hould be corrected to "Naomichi, Yamagishi, Japan <u>Barrier</u> Society" of the previous meeting minutes Closed
FPD M&C 150727-02	Polarizing Film Task Force	To rework for Doc.#5555A Closed
FPD M&C 150727-03	Polarizing Film Task Force	To submit Document #5555A, Revision to SEMI D50-0707, Test Method for Surface Hardness of FPD Polarizing Film with title change to: Test Method for Surface Hardness of FPD components for Cycle 7, 2015 Closed
FPD M&C 150727-04	LI OSNIMASA EQUENT	To send LOI for SNARF, Test Method of Water Vapor Barrier Property for Plastic Films with High Barrier for Electronic Devices, to SEMI by the end of August.
FPD M&C 150727-05	SEMI Staff	To circular the new SNARF to TC members and GCS to get approval before the next Japan TC Chapter meeting (November 11) Closed
FPD M&C 150727-06	Tadahiro Furukawa	To invite a speaker from Taiwan for STEP/Workshop Closed
FPD M&C 150206-07	SEMI Staff	To check 5 year review documents Closed





9 New Business

9.1 Documents Status Change

Tadahiro Furukawa proposed the following 2 documents status to be changed to "Inactive"

- SEMI D35-1103 (Reapproved 0709) Test Method for Measurement of Cold Cathode Fluorescent Lamp (CCFL) Characteristics
- SEMI D47-0307 Test Method for Measurement of Bent Cold Cathode Flourescent Lamps

Motion:	To change the document (D35 & D47) status to "Inactive"
By / 2 nd :	Ryoichi Watanabe (Japan Display) / Akira Kawaguchi (Otsuka Electronics)
Discussion:	None
Vote:	12 in favor and 0 opposed. Motion passed.

[FPD Metrology Japan TC Chapter Part]

10 Review of Previous Meeting Minutes

The committee reviewed the minutes of the previous meeting held on April 10, 2015.

Motion:	To approve the minutes of the previous meeting as written.	
By / 2 nd :	Akira Kawaguchi (Otsuka Electronics) / Keizo Ochi (Konica Minolta)	
Discussion:	None	
Vote:	12 in favor and 0 opposed. Motion passed.	
Attachment:	06_JA_FPD_M+C_Met_Previous_Mtg_Minutes_151111	

11 Task Force Reports

11.1 D31 Revision Task Force

Keizo Ochi reported for the D31 Revision Task Force that there were not particular activities.

Keizo Ochi proposed that the Task Force should be restructured for new activities and also co-leaders should be changed.

Motion:	To discharge Kose Tanahashi and Masao Kochi as the Task Force position due to non-attendance for lon	ig time.
---------	--	----------

By / 2nd: Akira Kawaguchi (Otsuka Electronics) / Keizo Ochi (Konica Minolta)

Discussion: None

Vote: 12 in favor and 0 opposed. Motion passed.

12 Old Business

12.1 Previous Meeting Action Items

Naoko Tejima reviewed the previous meeting action items.

Table 8 Previous Meeting Action ItemsFPD Materials & Components Japan TC Chapter

Item #	Assigned to	Details
FPD Metrology 150410-01	ISEMI Statt	To contact the co-leaders of D31 Revision TF (Kose Tanahashi and Masao Kochi) and ask their intention Closed

13 New Business

None.





[Common Part 2]

14 New Business

14.1 Having Workshop in future

FPD Coordination Group is planning to hold FPD STEP/Workshop, however, the contents should be discussed again and the new plan will be proposed at the next meeting.

15 Action Item Review

15.1 New Action Items

Naoko Tejima reviewed the new action items. These can be found in the New Action Items table at the beginning of these minutes.

16 Next Meeting and Adjournment

The next meeting of the FPD Materials & Components Japan TC Chapter is scheduled for Friday, February 5, 2016, 15:00-17:00, SEMI Japan, Tokyo, Japan.

The next meeting of the FPD Metrology Japan TC Chapter is scheduled in April. Date and Time are TBD.





Respectfully submitted by: Naoko Tejima Manager, Standards SEMI Japan Phone: +81.3.3222.5804 Email: ntejima@semi.org

Minutes approved by:

Tadahiro Furukawa (Yamagata University), Co-chair of FPD Materials & Components Japan TC Chapter	Jan. 7, 2016
Yoshi Shibahara (Fujifilm), Co-chair of FPD Materials & Components Japan TC Chapter	Jan. 6, 2016
Ryoichi Watanabe (Japan Display), Co-chair of FPD Metrology Japan TC Chapter	Jan. **, 2016
Akira Kawaguchi (Otsuka Electronics), Co-chair of FPD Metrology Japan TC Chapter	Jan. **, 2016

Table 9 Index of Available Attachments ^{#1}

#	Title
1	SEMI_Staff_Report_151111
2	TW_FPD_Liaison_Report_151111
3	JA_FPD_M+C_Previous_Mtg_Minutes_151111
4	Ballot_Report_for_5555A_151111
5	New_SNARF_of_Water_Vapor_Barrier_Propoerty_150727
6	JA_FPD_M+C_Met_Previous_Mtg_Minutes_151111

#1 Due to file size and delivery issues, attachments must be downloaded separately. A .zip file containing all attachments for these minutes is available at www.semi.org. For additional information or to obtain individual attachments, please contact Naoko Tejima at the contact information above.